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Docket No.: EHF 2001,0167 P

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By: 

Date: May 6, 2004

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 09/873,230 Confirmation No: 4487
Applicant : Norbert Benesch
Filed : June 4, 2001
Title : Method and Device for Optically Monitoring Fabrication
Processes of Finely Structured Surfaces in a Semiconductor
Production
Art Unit : 2621
Examiner : to be assigned
Docket No. : EHF 2001,0167 P
Customer No. : 24131

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Technology Center 2600

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner for Patents

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

Japanese Patent Abstract JP 61 169 750 (Tanabe), dated July 31, 1986;

Japanese Patent Abstract JP 62 200 251 (Nakai et al.), dated September 3, 1987;

Japanese Patent Abstract JP 9 191 032 (Yoshitake et al.), dated July 22, 1997;

Japanese Patent Abstract JP 9 318 330 (Ishimaru), dated December 12, 1997;

German translation of Japanese Office Action dated March 10, 2004.

In accordance with 37 C.F.R. 1.97(e) the undersigned herewith states that each item of information contained in the information disclosure statement was first cited in a

communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

Respectfully submitted,



For Applicants

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Date: May 6, 2004

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